

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**RECEIVED****CENTRAL FAX CENTER****JUN 28 2005**

Applicants: Heng Liu

Title: Chemical Vapor Deposition Reactor

Application No.: 10/621,049

Filing Date: July 15, 2003

Examiner: Ram N. Kackar

Group Art Unit: 1763

Docket No.: M-15626 US

Confirmation No.: 8846

Irvine, California  
June 28, 2005Via Facsimile to (703) 872-9306Mail Stop AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action dated December 29, 2004, please amend the above-identified application as follows.